

Fig. 2

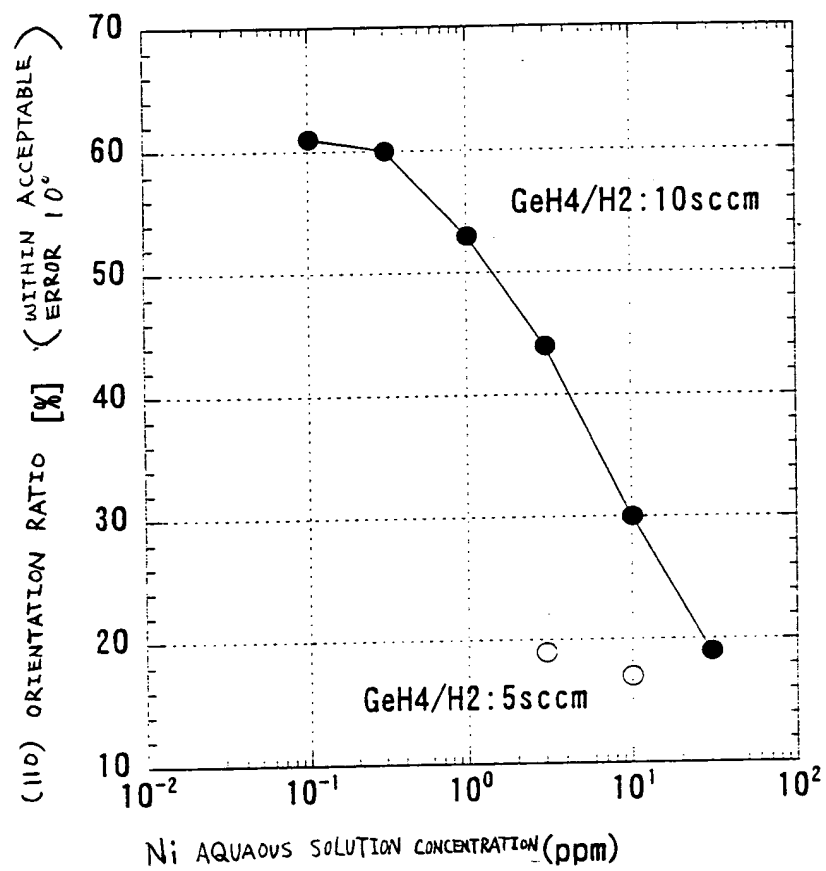
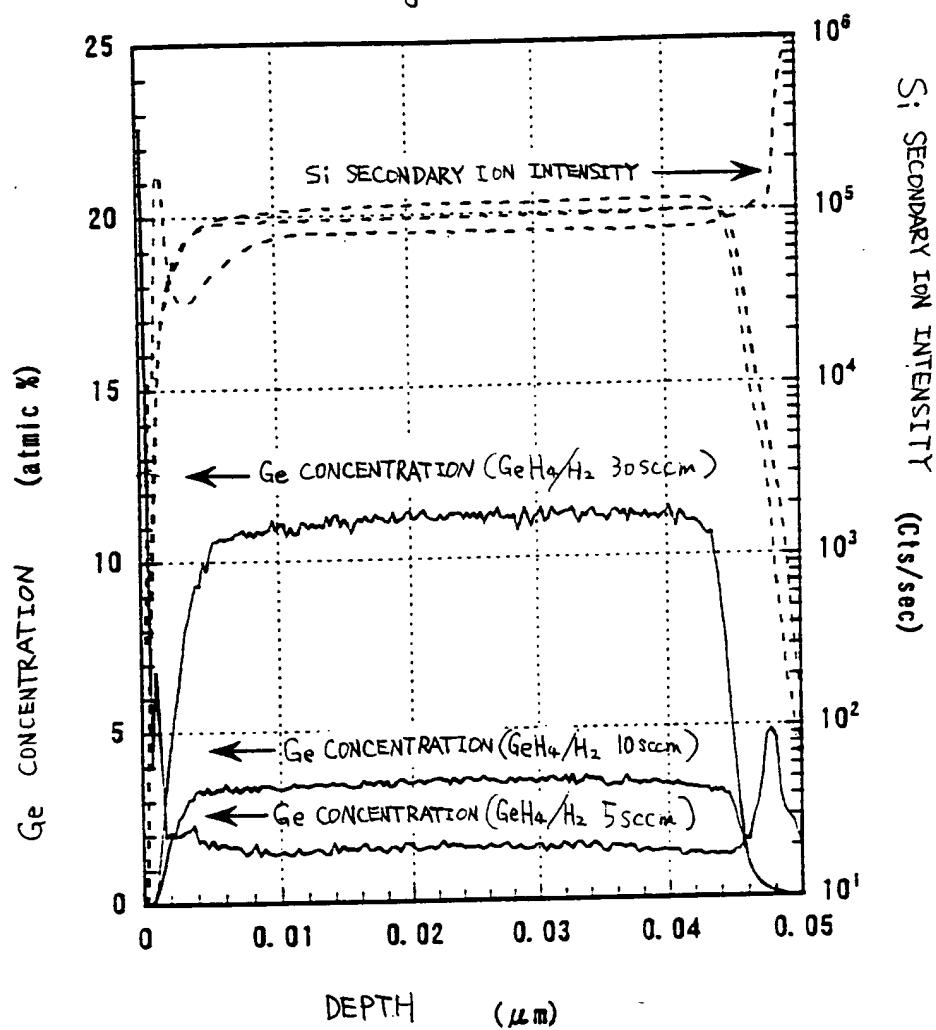


Fig. 3



3810

Fig. 4

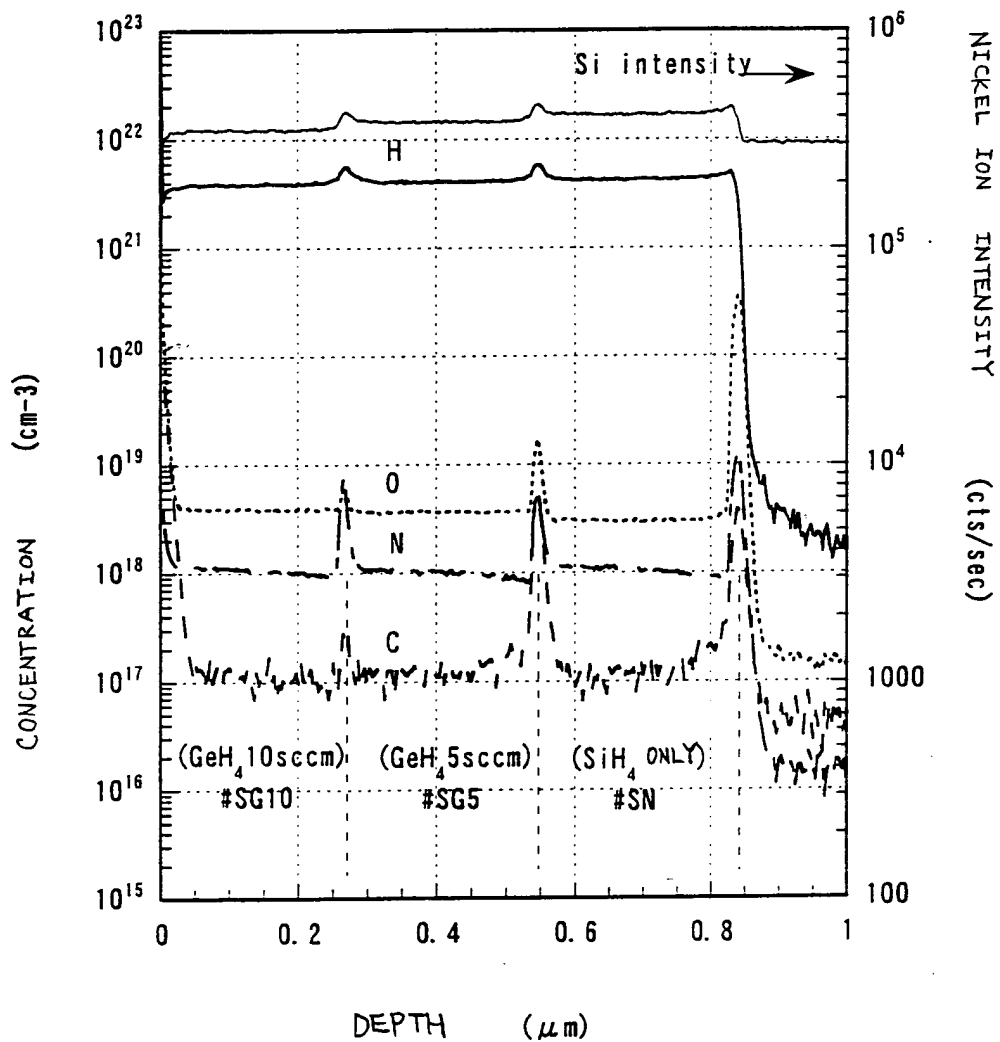
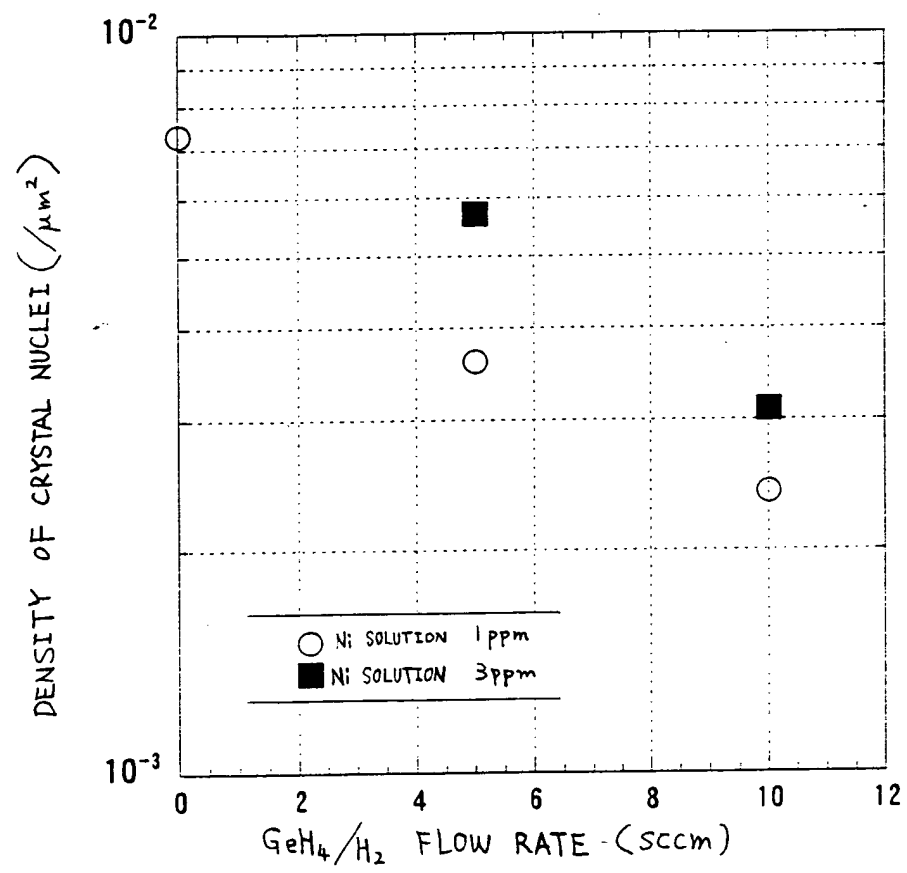
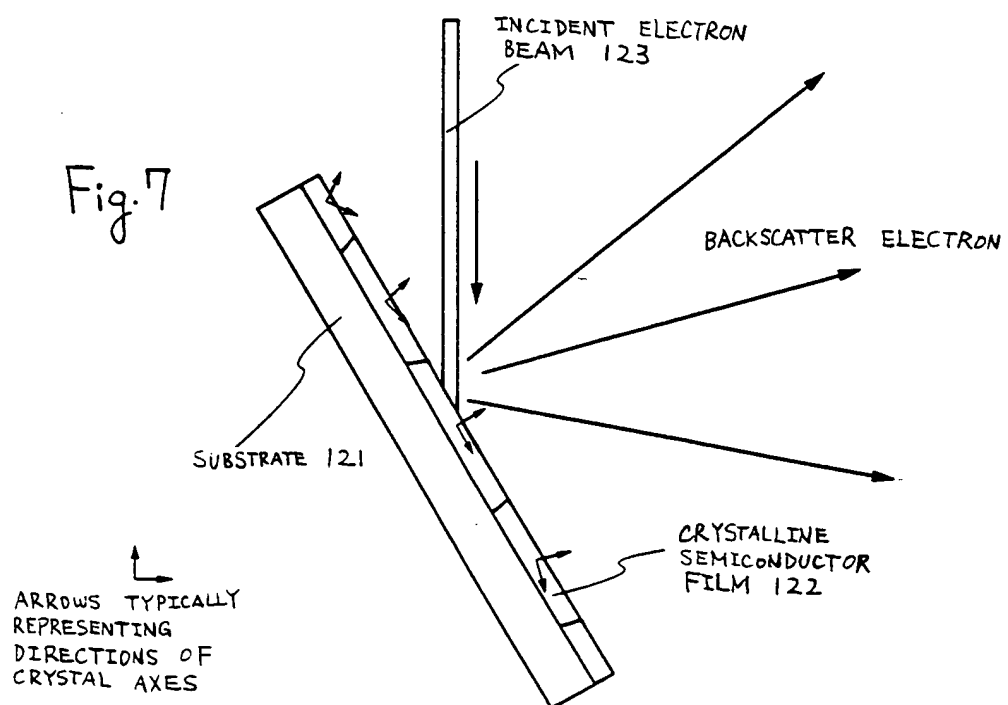
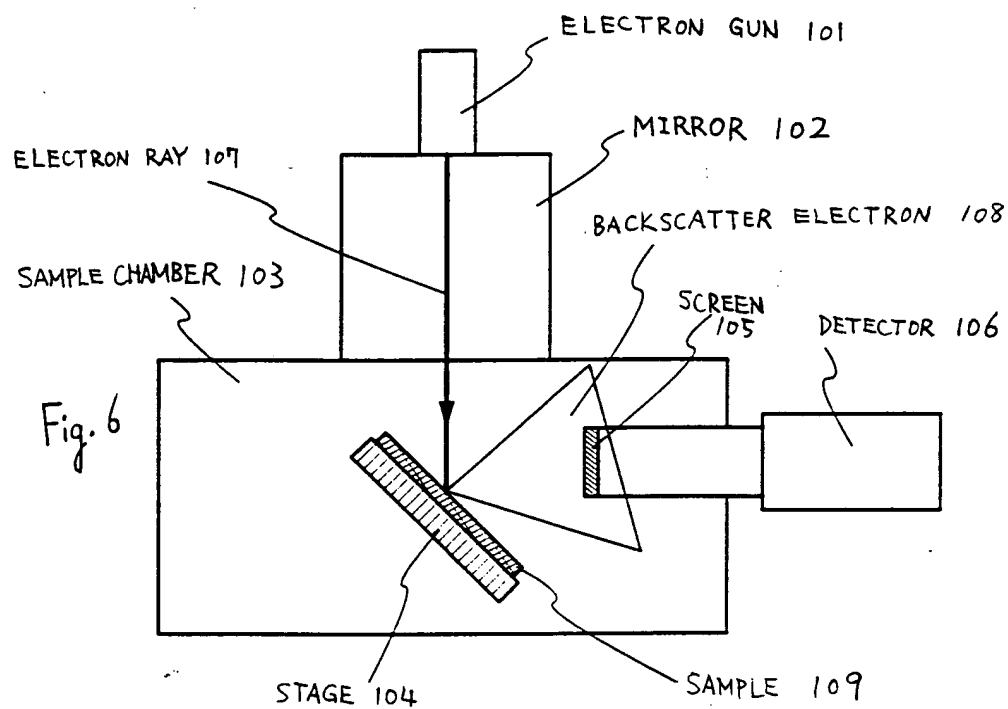


Fig. 5



3010



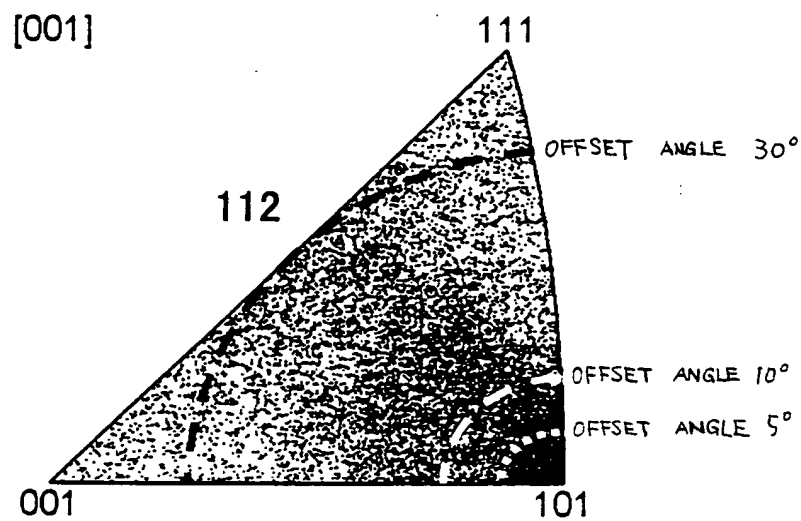


Fig. 8A PLOTS OF ALL OF MEASUREMENT POINTS IN MAPPING MESUREMENT

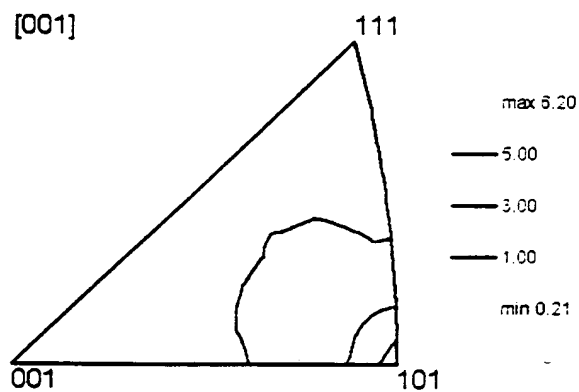
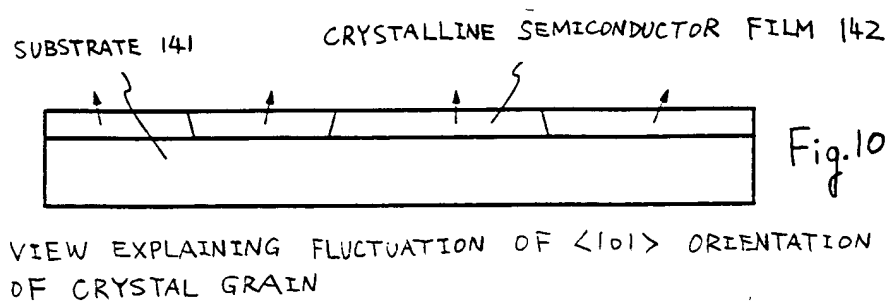
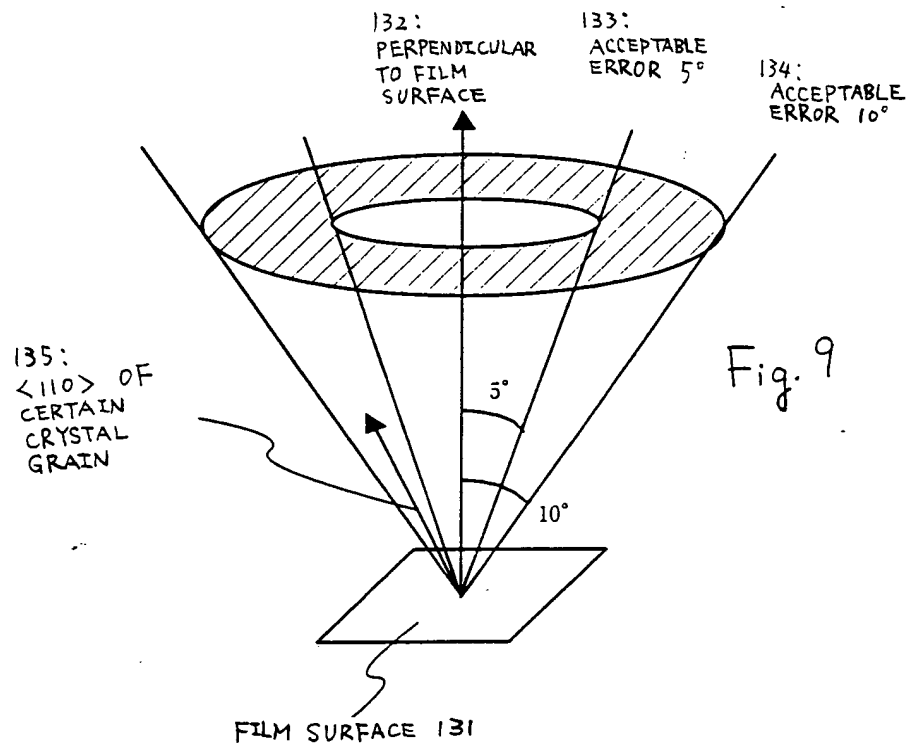


Fig. 8B EXAMPLE OF TRANSLATING CONCENTRATION OF POINTS OF Fig. 8A INTO CONTOUR





3013

Fig. 11A

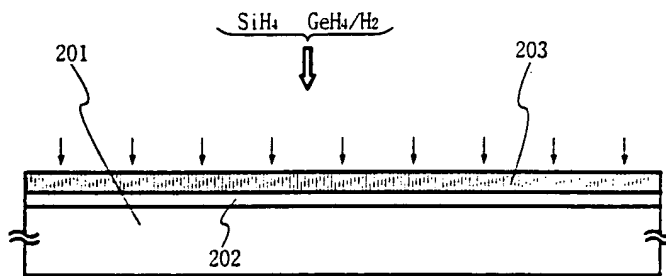


Fig. 11B

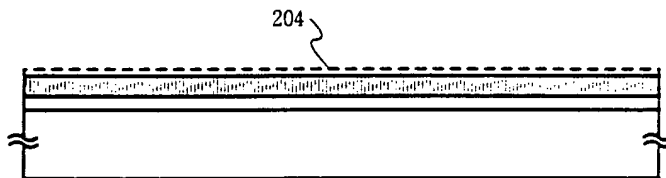


Fig. 11C

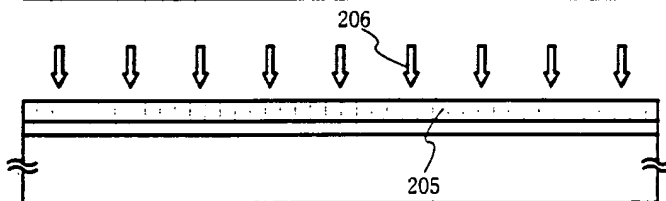
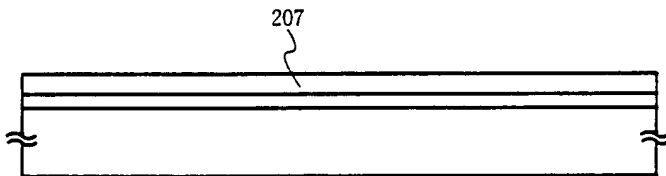
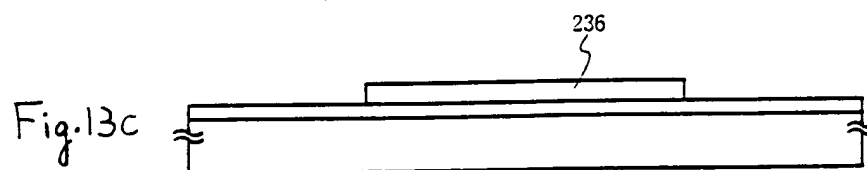
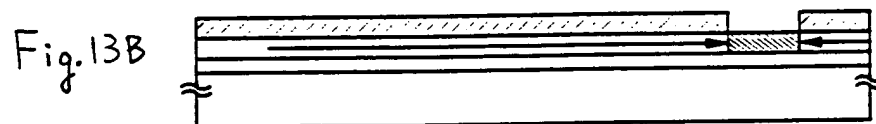
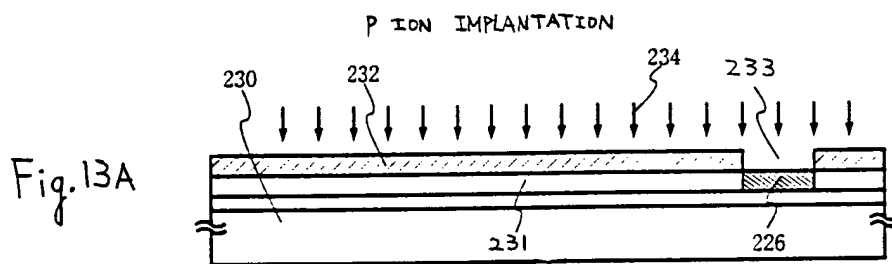
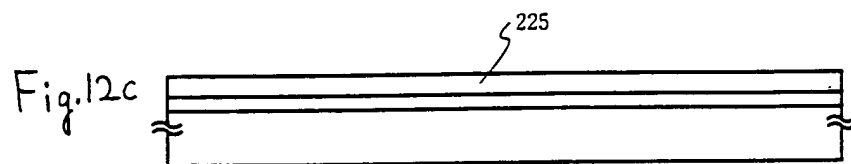
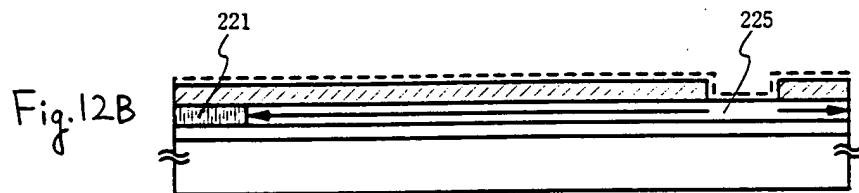
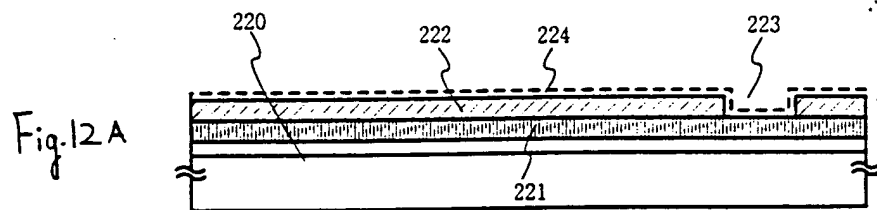
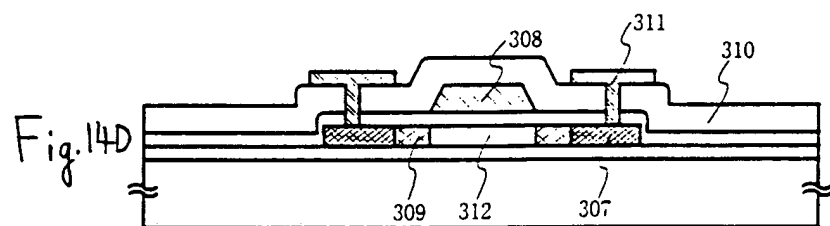
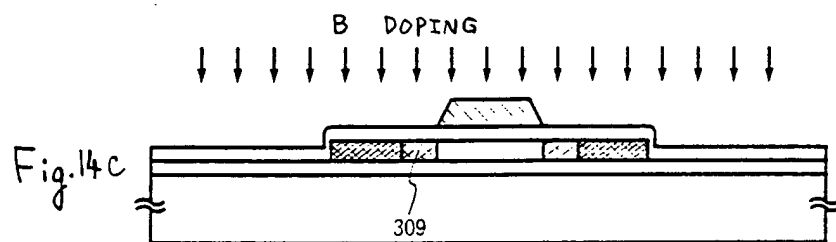
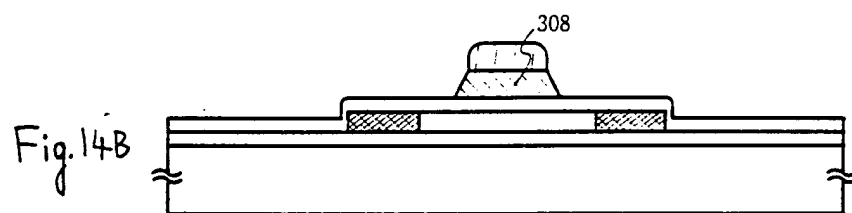
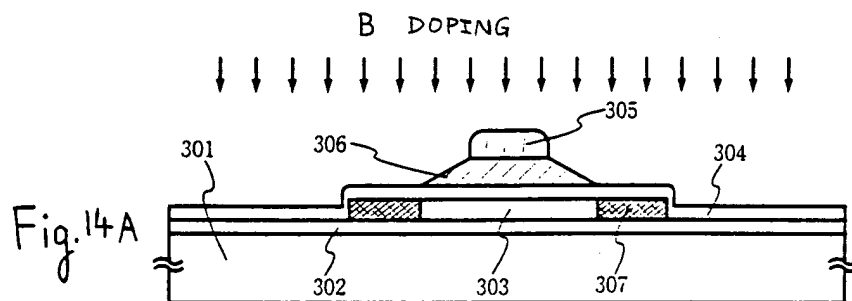


Fig. 11D







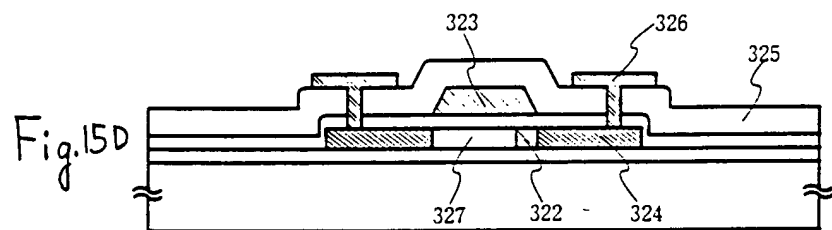
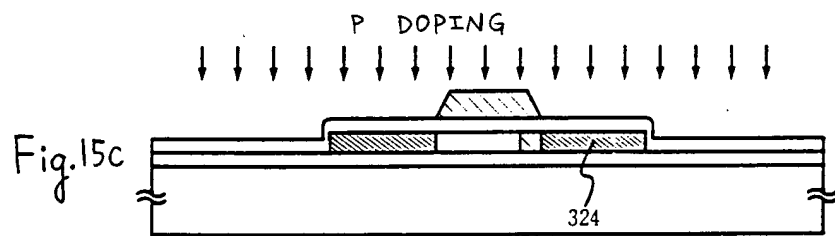
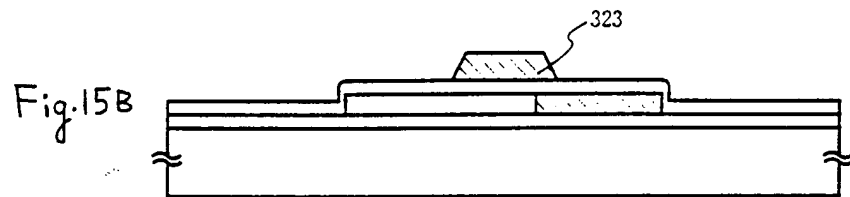
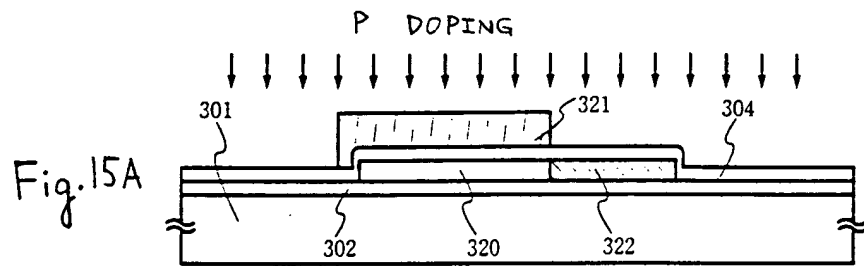


Fig. 16A

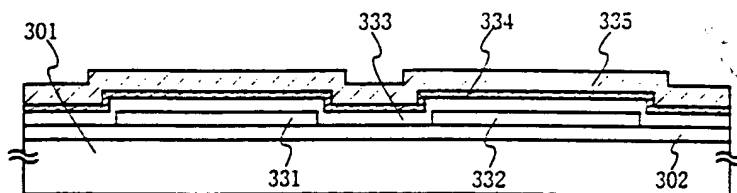


Fig. 16B

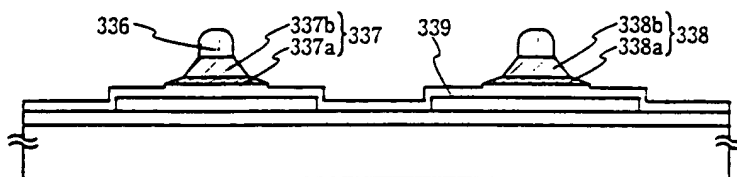


Fig. 16C

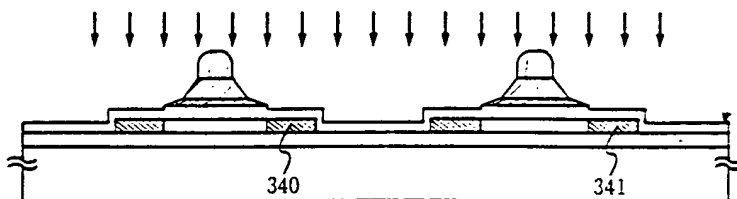


Fig. 16D

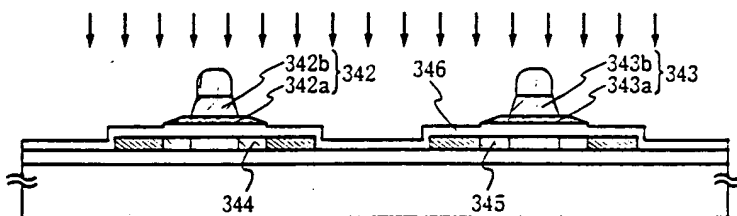


Fig. 16E

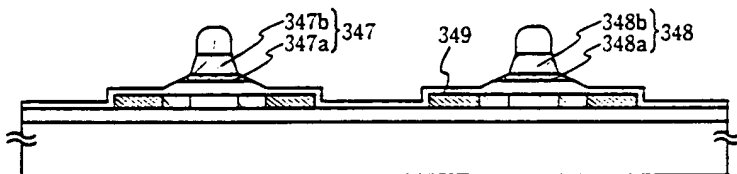


Fig. 16F

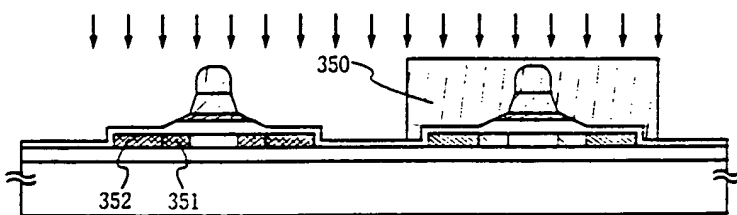


Fig. 16G

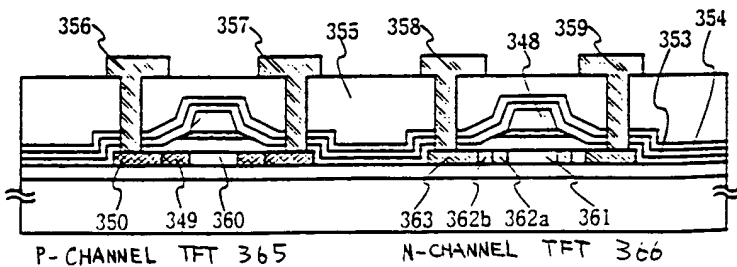


Fig. 17

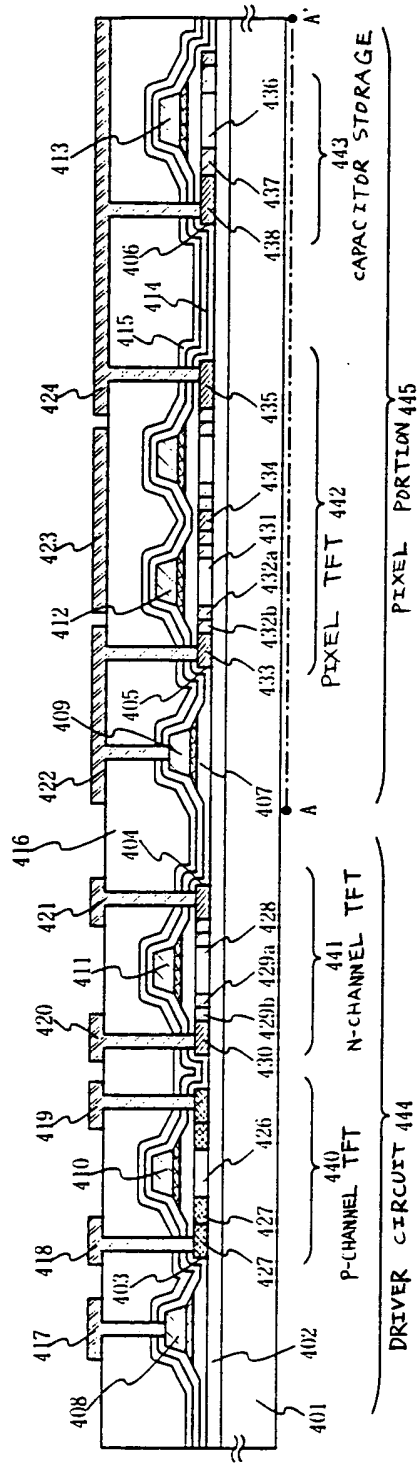
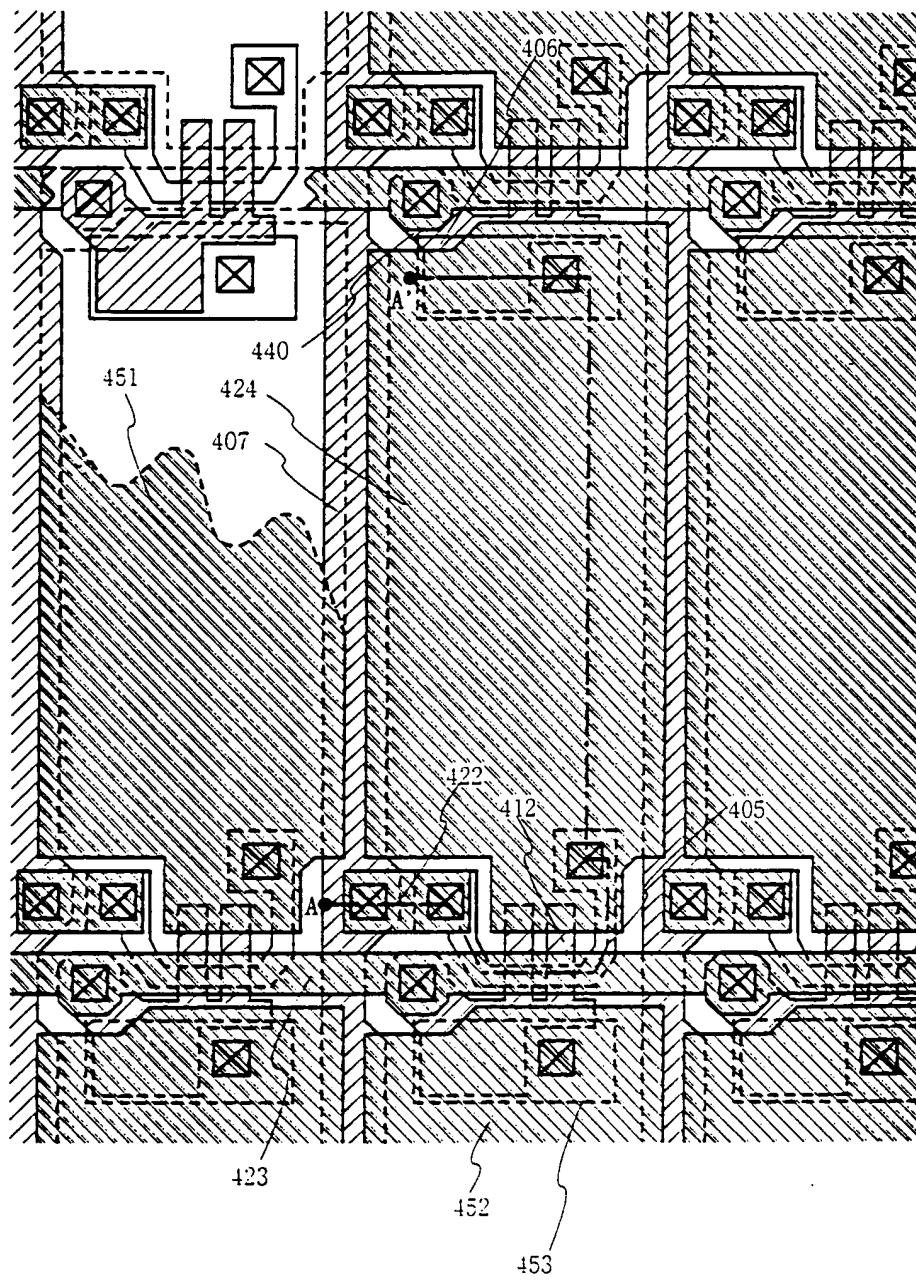


Fig. 18



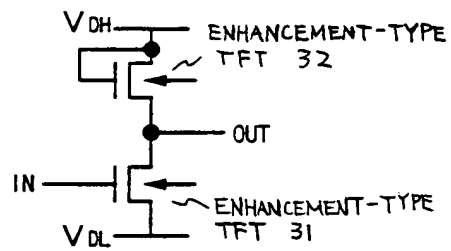


Fig. 19A EEMOS CIRCUIT

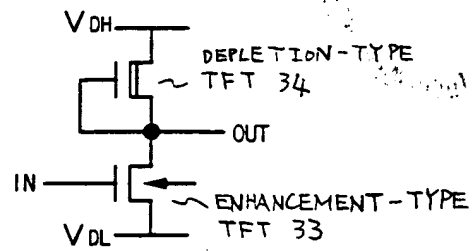


Fig. 19B EDMOS CIRCUIT

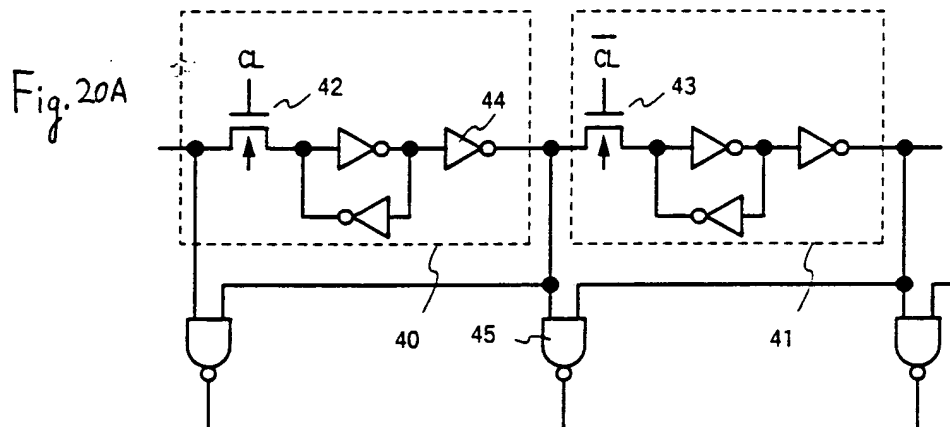
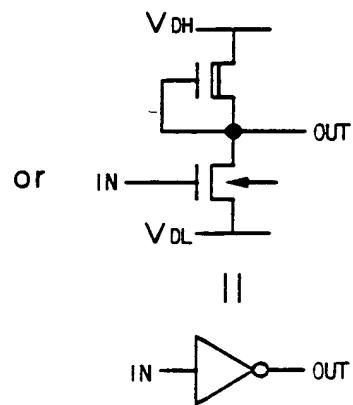
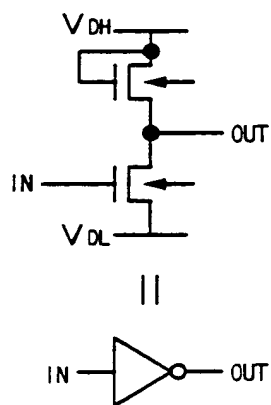


Fig. 20B





DIRECTION OF LIGHT

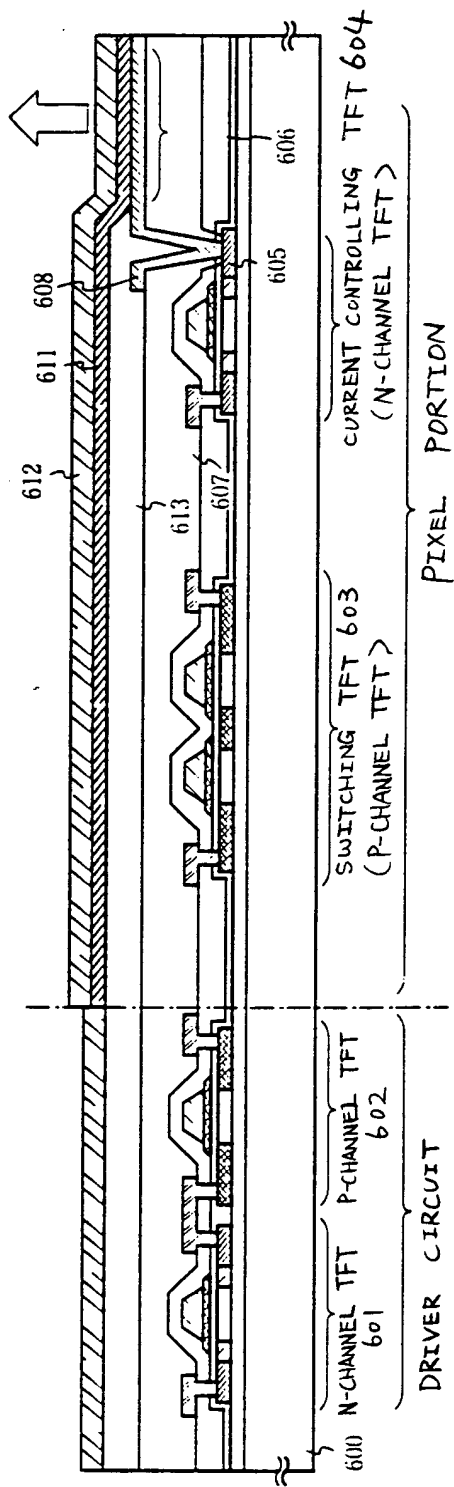


Fig. 21

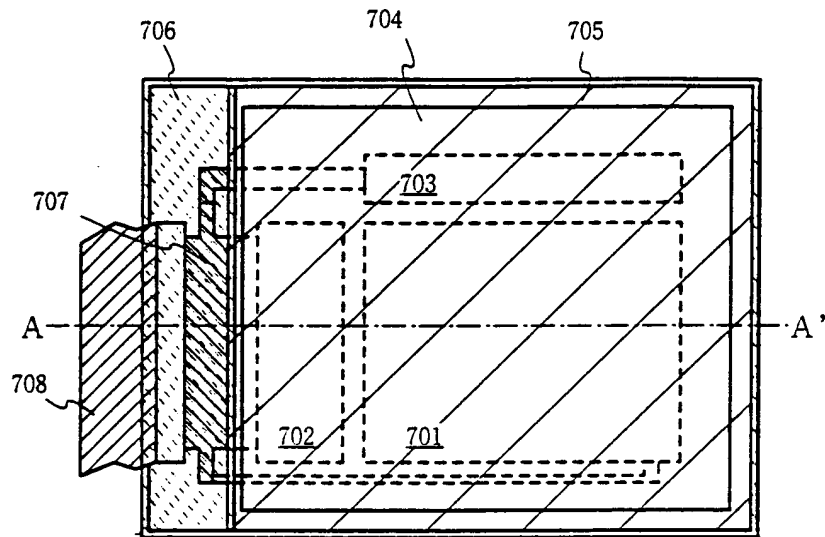


Fig. 22A

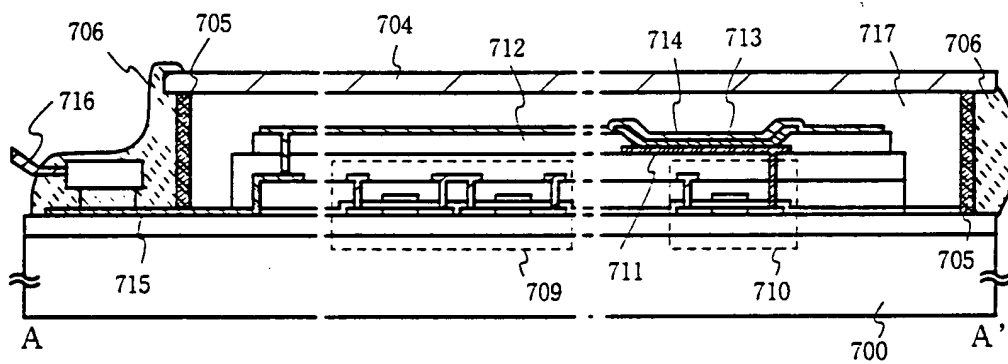
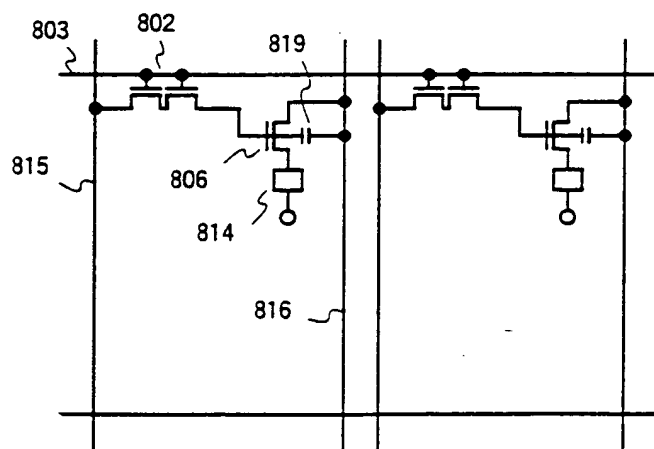
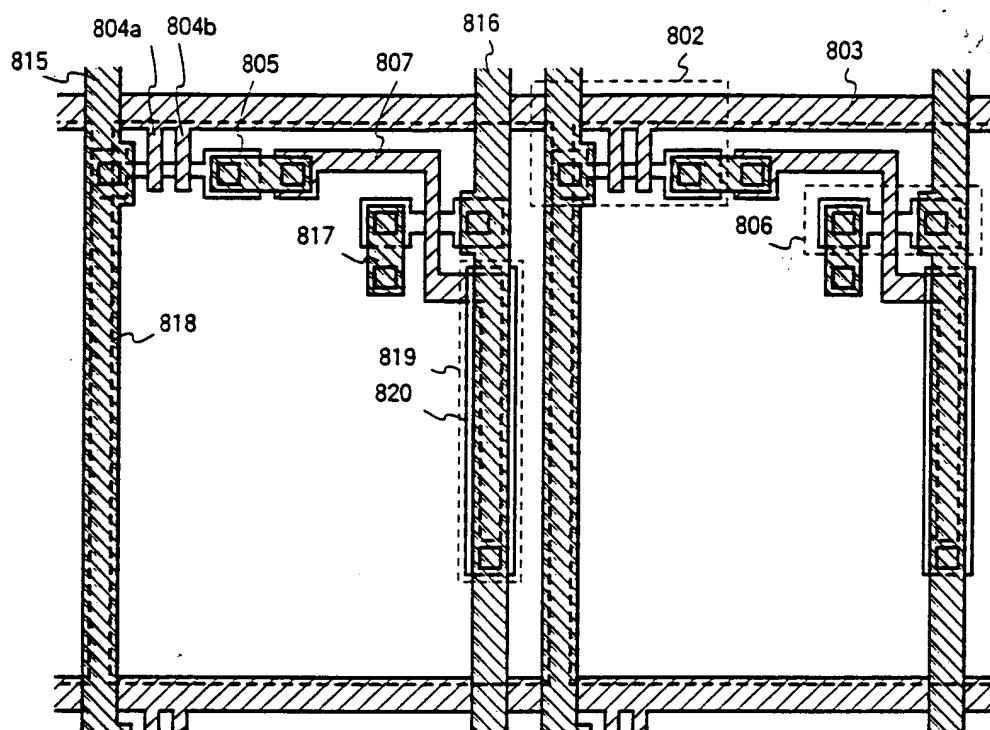


Fig. 22B



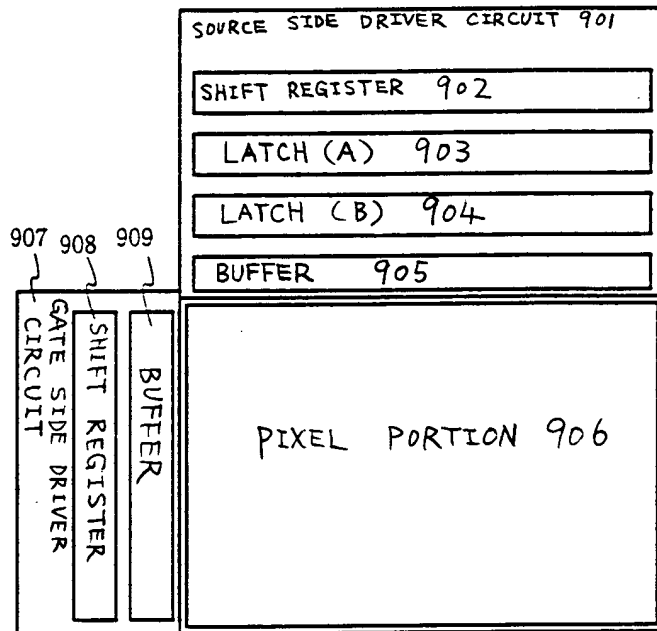


Fig. 24

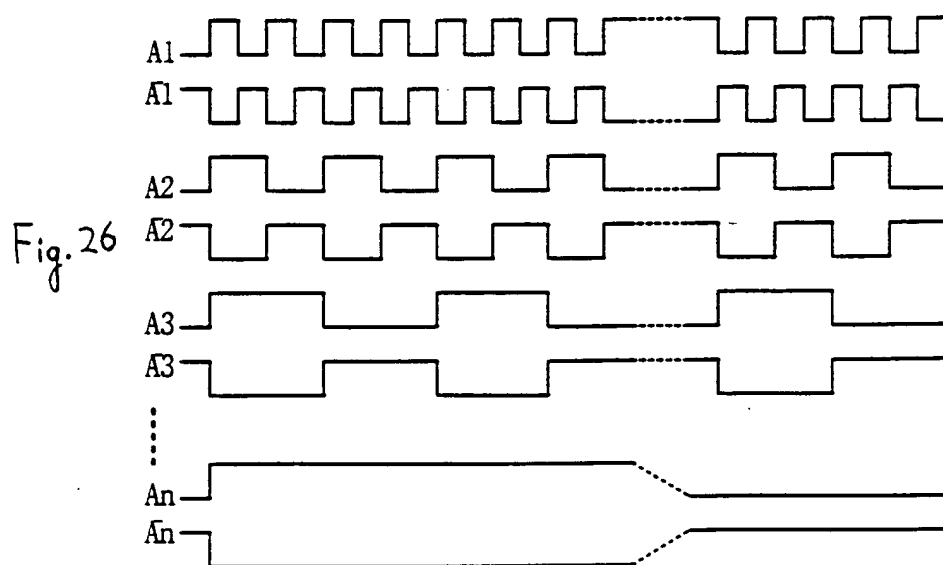
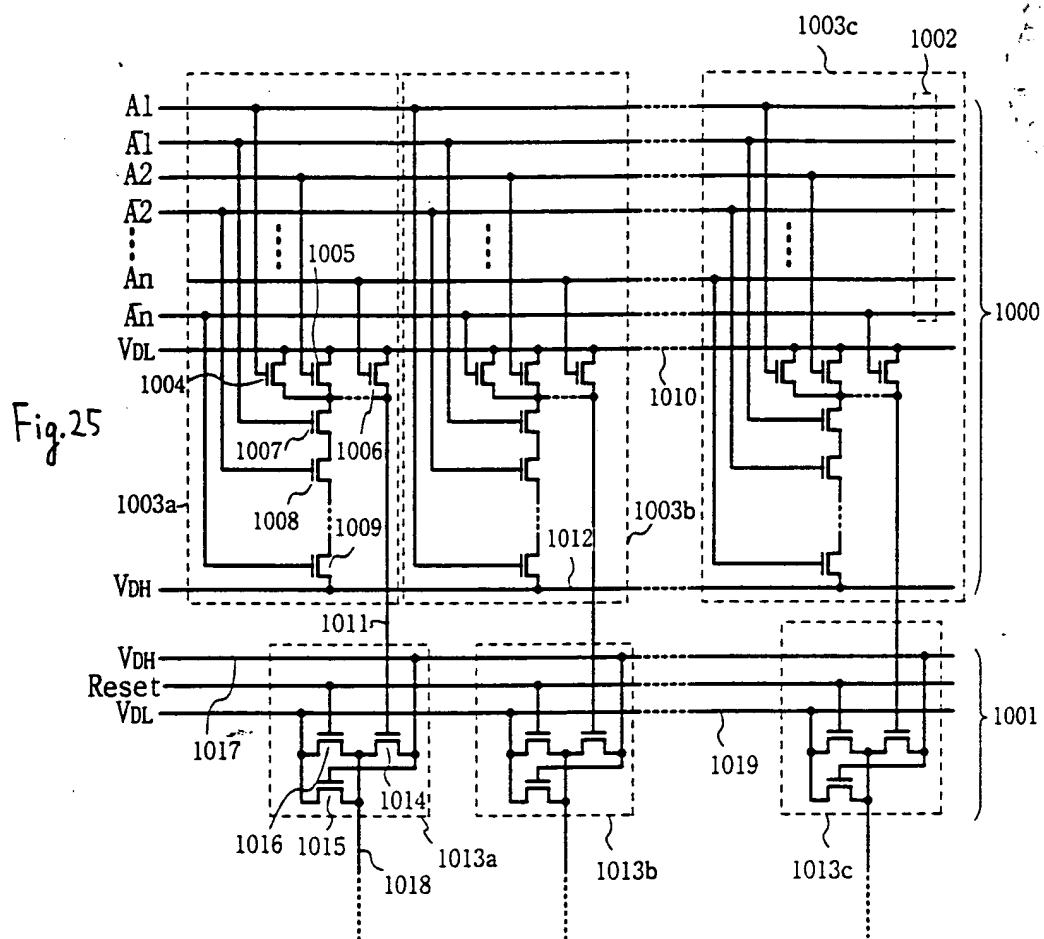
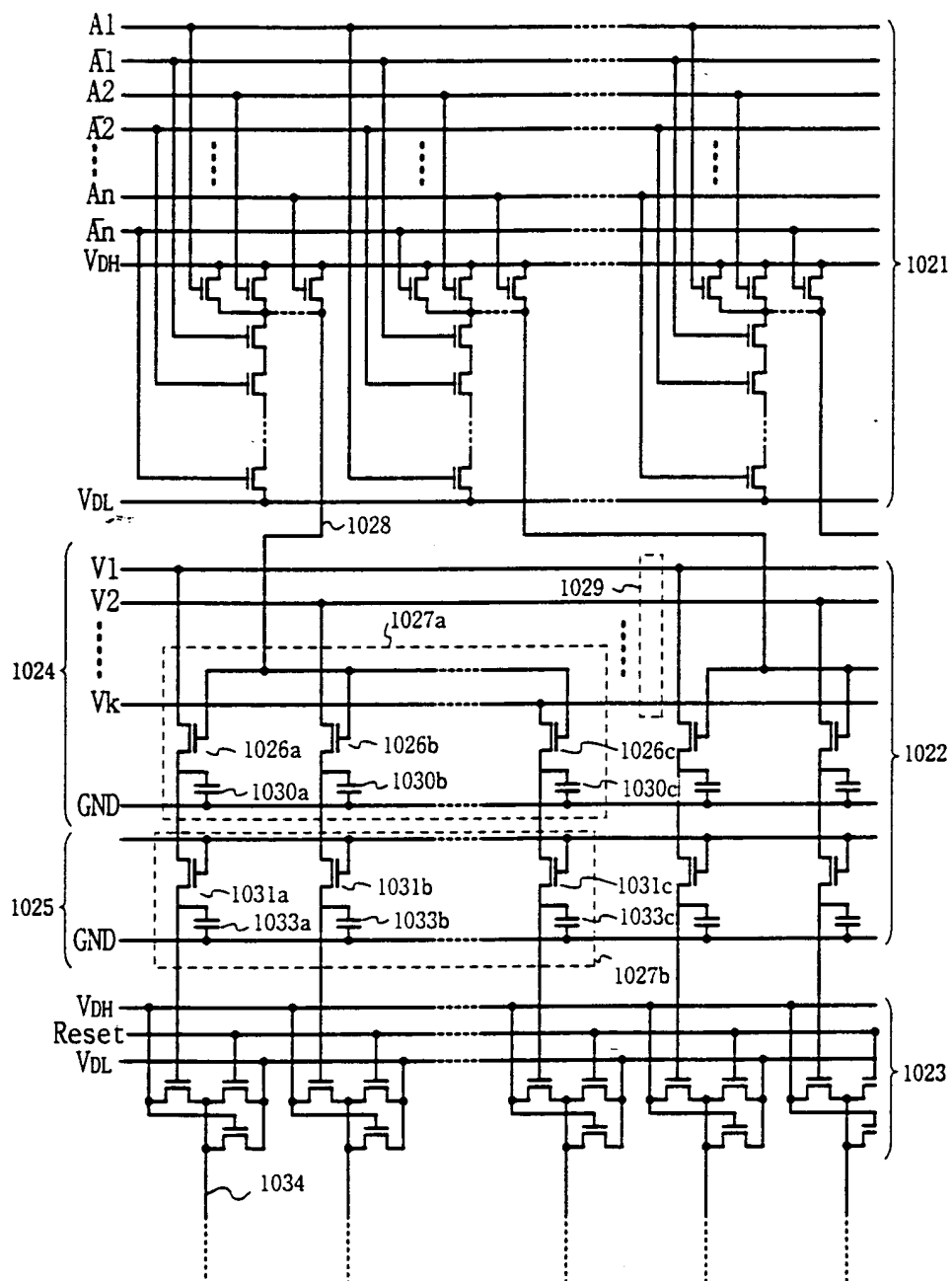


Fig. 27





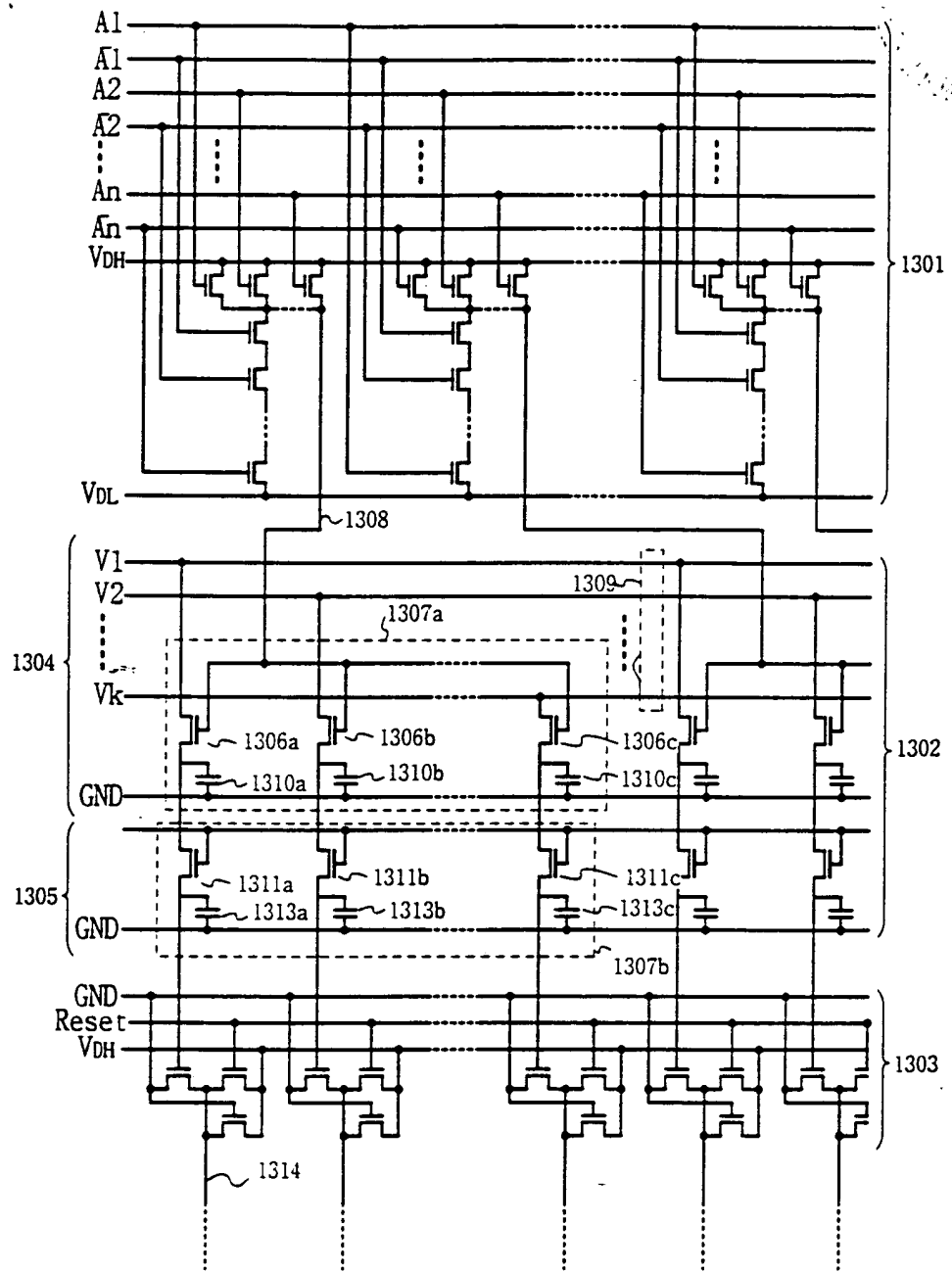
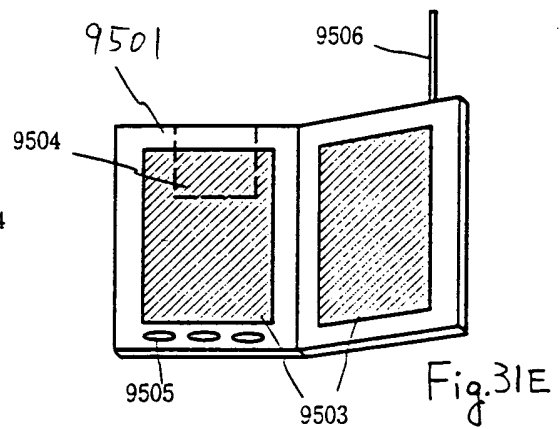
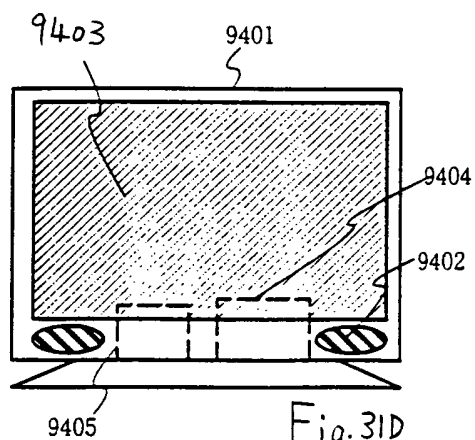
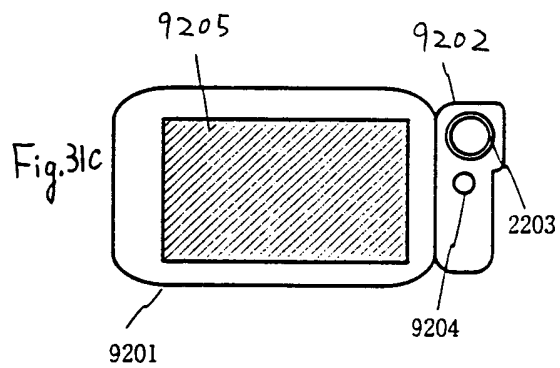
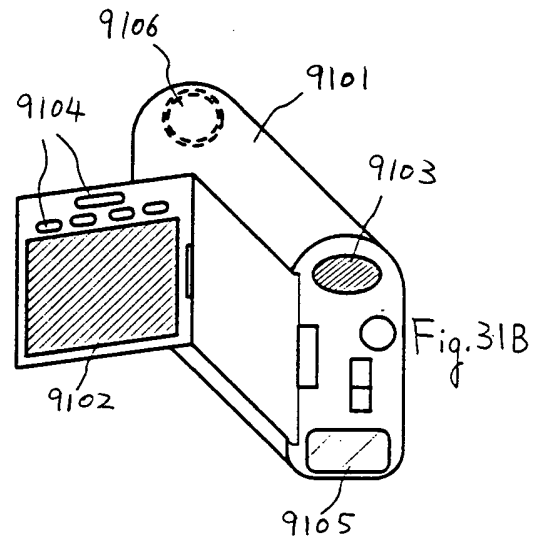
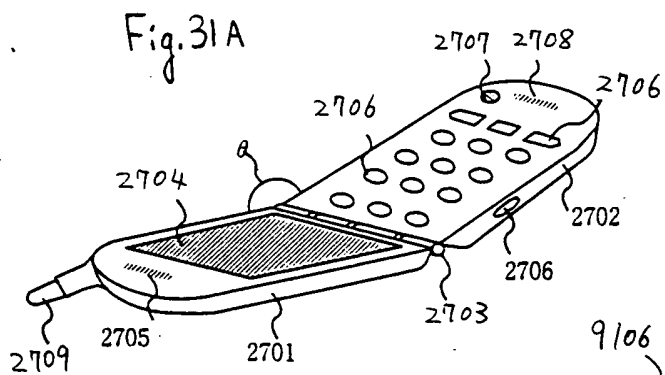
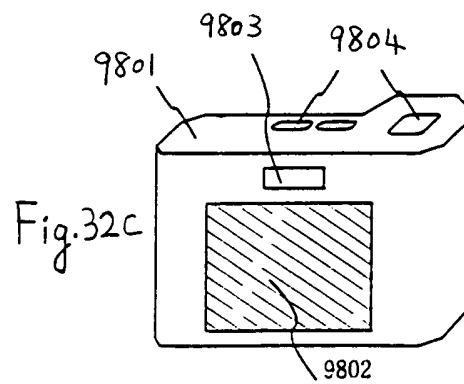
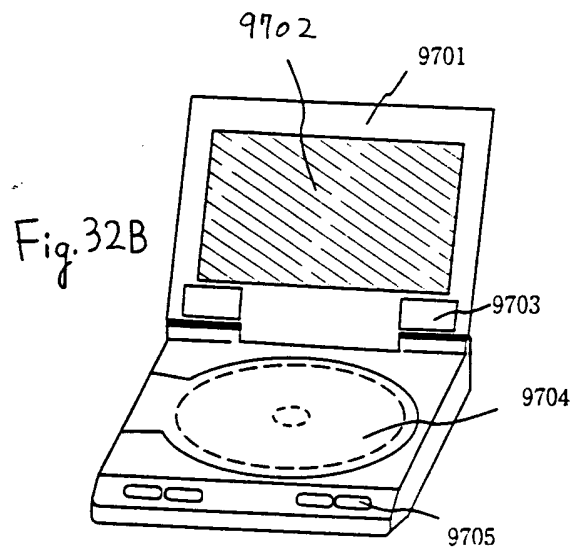
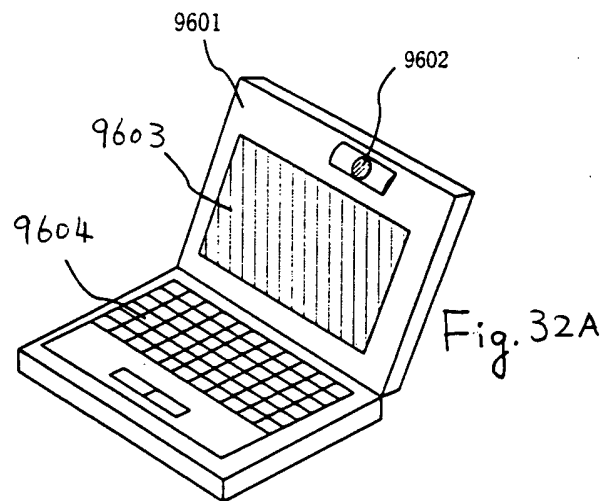


Fig. 30







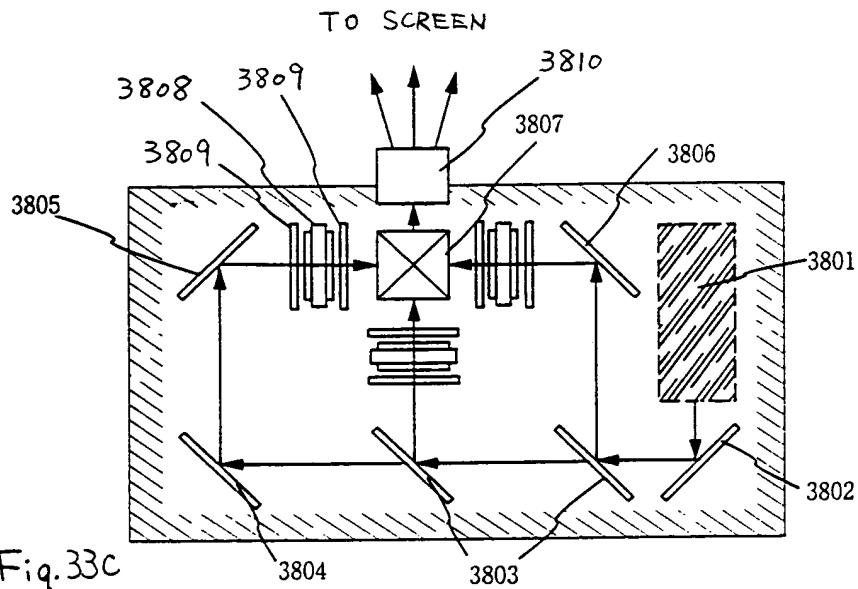
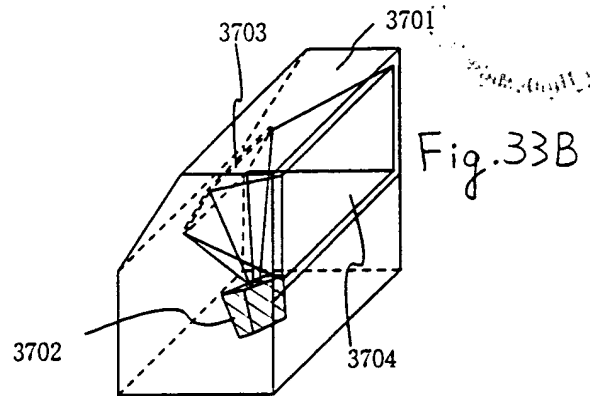
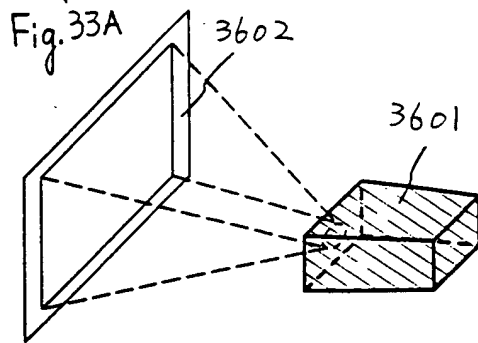


Fig. 33C  
PROJECTING APPARATUS  
(THREE PLATE TYPE)

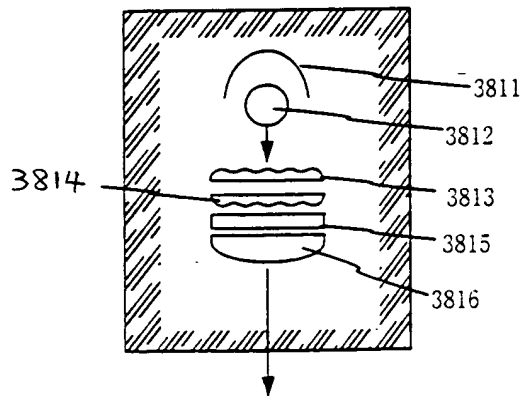


Fig. 33D  
LIGHT SOURCE  
OPTICAL SYSTEM

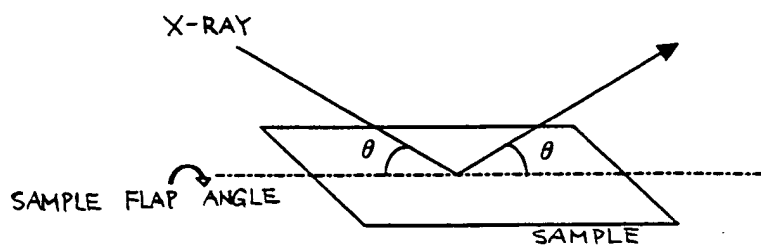


Fig. 34

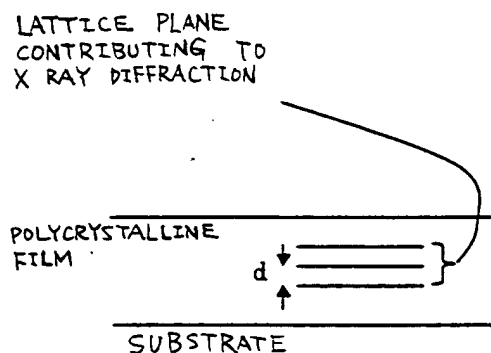


Fig. 35A  
IN CASE OF FLAP ANGLE  $0^\circ$

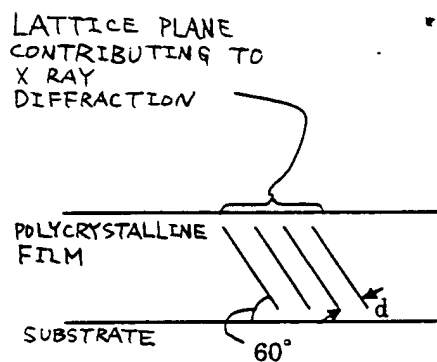


Fig. 35B  
IN CASE OF FLAP ANGLE  $60^\circ$



Fig. 36

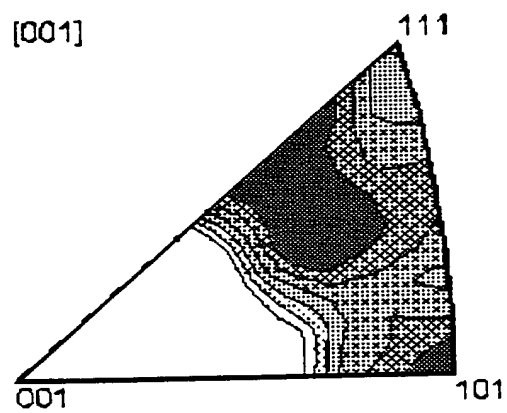


Fig. 37A CRYSTALLIZATION

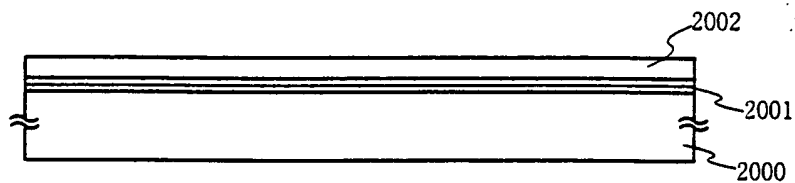


Fig. 37B FORMATION OF BARRIER LAYER AND FORMATION OF SEMICONDUCTOR FILM

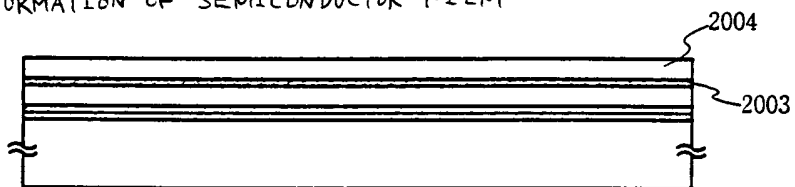


Fig. 37C DOPING WITH NOBLE GAS

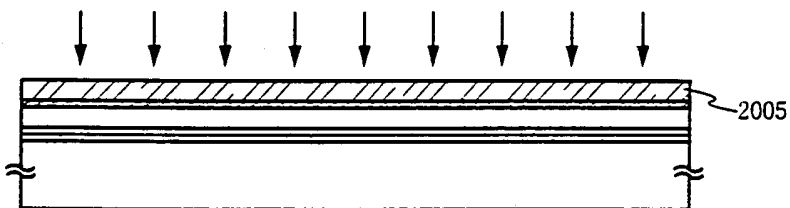
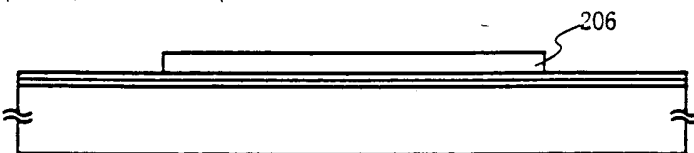


Fig. 37D GETTERING



Fig. 37E FORMATION OF SEMICONDUCTOR ISLAND



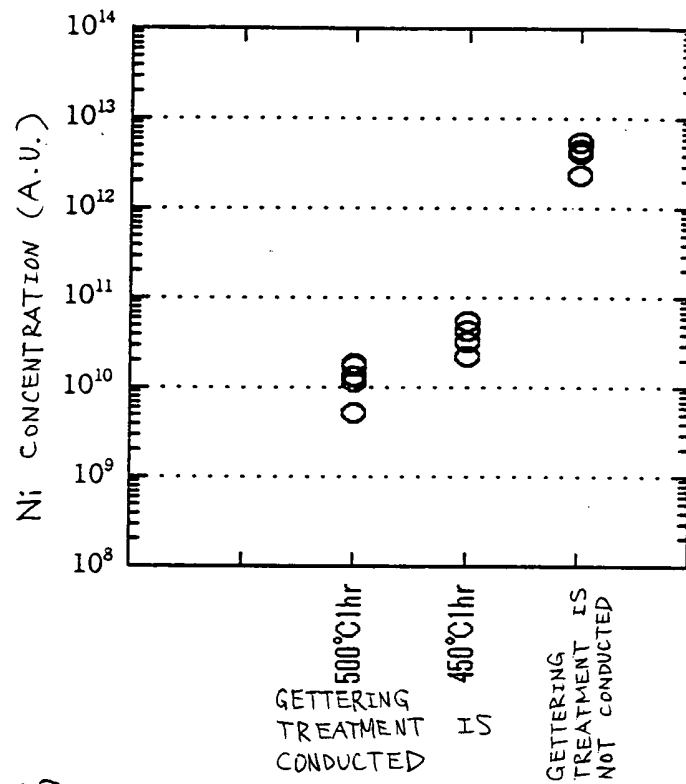


Fig. 38

